

Amendments to the Claims:

This listing of claims will replace all prior versions, and listings, of claims in the application:

Listing of Claims:

1-4 (cancelled)

5. (currently amended) An apparatus ~~for receiving, storing, transmitting, and releasing manufactured products, said apparatus suitable for insertion into the manufacturing flow at various stages of product fabrication,~~ comprising:

a computer-controlled chamber for maintaining an internal temperature specified environments; ~~said chamber having a computer-controlled~~ an entry and exit;

a transport system connecting said entry and exit, ~~said system including movable platforms suitable for transporting [[said]] a product into and out of the chamber; said system designed to create waiting lines for said product loaded on said platforms; and computer-controlled monitors for position and time of said platforms, said monitors operable to achieve a balanced product throughput through said chamber.~~

a computer-controlled reflow station connecting to the chamber, having a reflow-temperature profile with a end-point temperature higher than room-temperature; and

the internal temperature of the computer-controlled chamber comparable to the end-point temperature.

6. (currently amended) The apparatus according to Claim 5 wherein said computer-controlled chamber maintains environments include computer-controlled gaseous ambient ~~[[,]]~~ and humidity, ~~and temperature.~~

7. (currently amended) The apparatus according to Claim 5 wherein said product comprises flip-chip semiconductor devices on substrates.

8. (currently amended) The apparatus according to Claim 5 wherein ~~said waiting lines are structured as~~ the chamber comprises horizontally rotatable carousels adapted to carry flip-chip semiconductor devices on substrates.

9. (currently amended) The apparatus according to Claim 5 wherein ~~said waiting lines~~

~~are structured as~~ the chamber comprises vertically rotatable wheels adapted to carry flip-chip semiconductor devices on substrates.

10. (currently amended) The apparatus according to Claim 5 wherein ~~said waiting lines are structured as~~ the chamber comprises elongated conveyor systems adapted to carry flip-chip semiconductor devices on substrates.

11. (currently amended) The apparatus according to Claim 5 ~~wherein said inlets and outlets are supported by~~ further comprising sensors ~~feeding their observations back to said computer control.~~

12-15 (cancelled)